EE 332: Devices and Circuits II

Lecture 2: MOS Devices (Part 1)

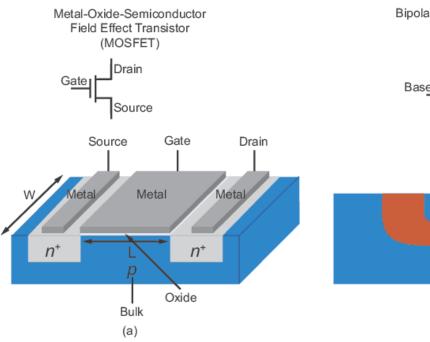
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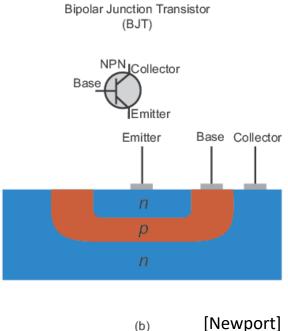
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MOSFET vs. BJT Devices

- Bipolar junction transistor (BJT)
 - Works based on the diffusion current
 - Can operate at higher frequencies
 - Lower noise
 - Larger intrinsic gain (g_mr_o)
- Metal-oxide-semiconductor fieldeffect transistor (MOSFET)
 - Works based on the drift current
 - Very scalable and compact
 - Lower power (excellent for mixedsignal ICs)
 - Widely used in today's ICs

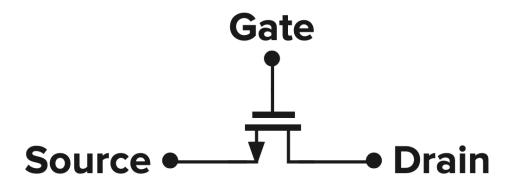




We only focus on MOSFETs in this course!

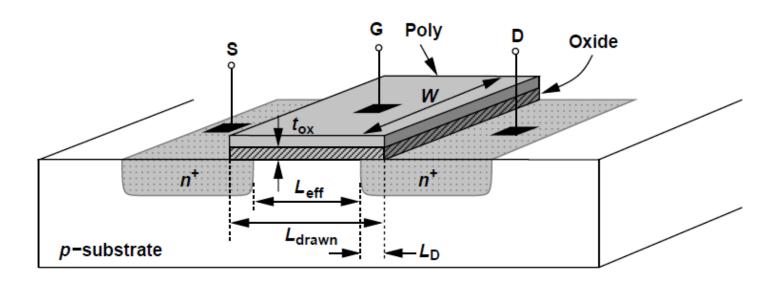
(However methods and circuit topologies are very similar between MOS and BJTs)

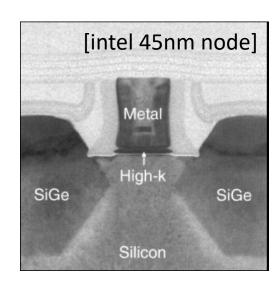
MOSFET as a Switch



- When gate voltage is high, device is on (Recall this from CMOS logics in EE331).
- Source and drain are interchangeable.
- But,
 - At what gate voltage does the device turn on?
 - How much is the resistance between S and D?
 - What limits the speed of the device?

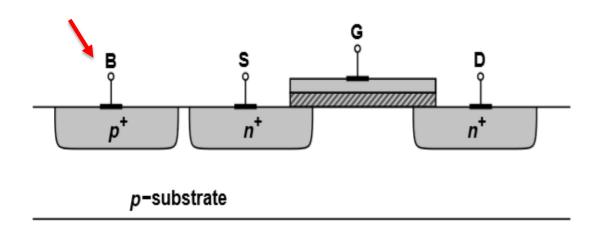
MOSFET Structure

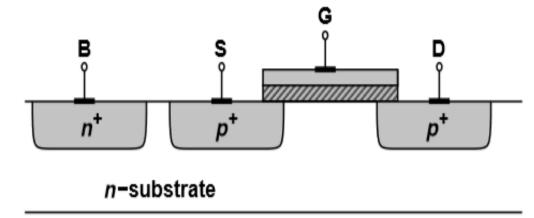




- n-type MOS (NMOS) has n-doped source (S) & drain (D) on p-type substrate ("bulk" or "body")
- S/D junctions "side-diffuse" during fabrication so that effective length $L_{eff} = L_{drawn} 2L_D$
- Typical values are $L_{eff} \approx 10$ nm and $t_{ox} \approx 15$ Å
- The S terminal provides charge carriers and the D terminal collects them.
 - As voltages at the three terminals changes, the source and drain may exchange roles (Device structure is symmetric).

MOSFET Structure

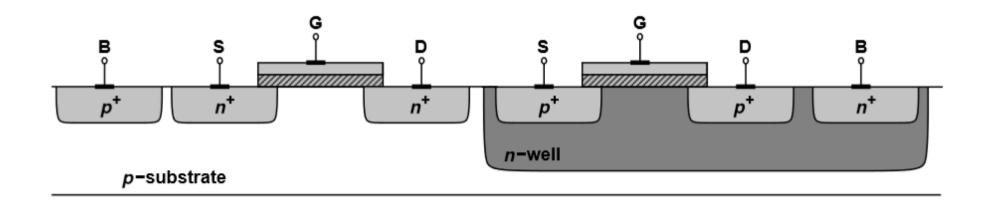




- MOSFETs actually have four terminals.
- Substrate potential greatly influences device characteristics.
- Typically S/D junction diodes are reversed-biased and the NMOS substrate is connected to the most negative supply in the system.

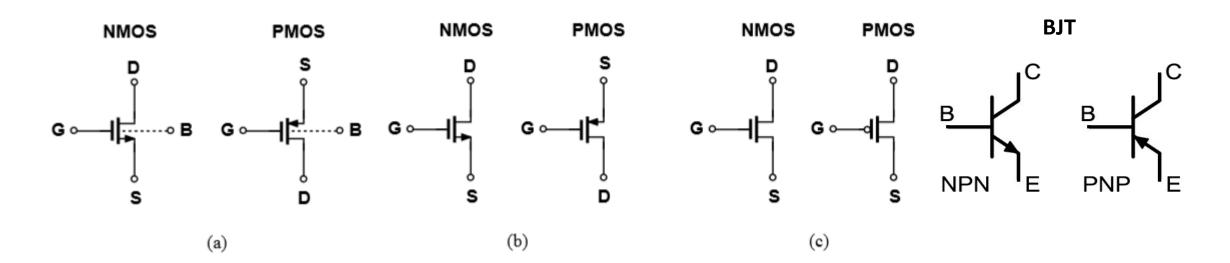
• PMOS is obtained by inverting all of the doping types (including the substrate).

MOSFET Structure

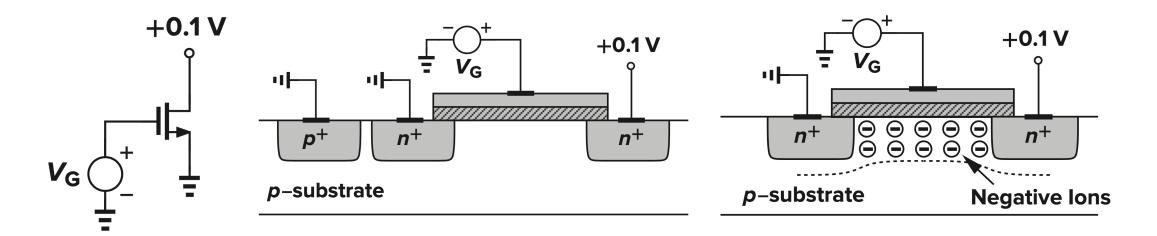


- In complementary MOS (CMOS) technologies both NMOS (NFET) and PMOS (PFET) are needed and fabricated on the same wafer.
- In today's CMOS, the PMOS is fabricated in an *n*-well, where the *n*-well is tied to the most positive supply voltage (normally called VDD).

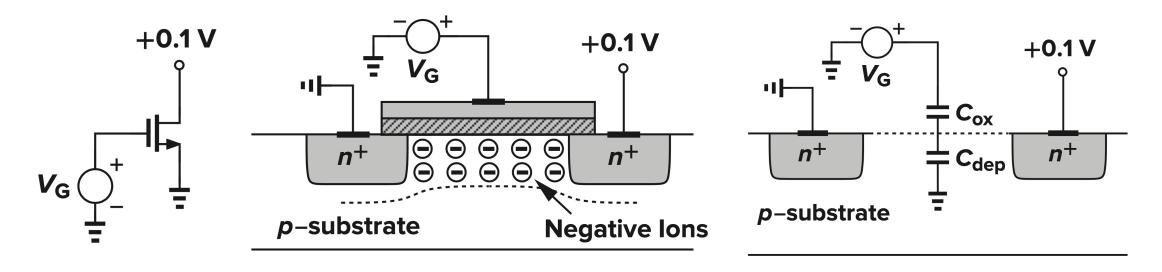
MOS Symbols



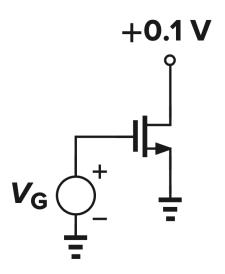
- Substrate is denoted by "B" (bulk).
- PMOS source is positioned on top since it has a higher potential than the gate.
- Most circuits have NMOS and PMOS bulk tied to ground and V_{DD} , respectively, so we tend to omit the connections (b,c).
- Digital circuits tend to incorporate "switch" symbols (c).

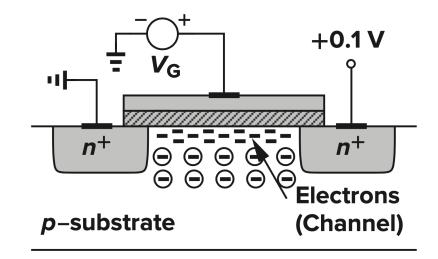


- As V_G increases from zero, holes in *p*-substrate are repelled leaving negative ions behind to form a depletion region.
- There are no charge carriers, so no current flow.



- Increasing V_G further increases the width of the depletion region and the potential at the oxide-silicon interface.
- Structure resembles voltage divider consisting of gate-oxide capacitor and depletion region capacitor in series.





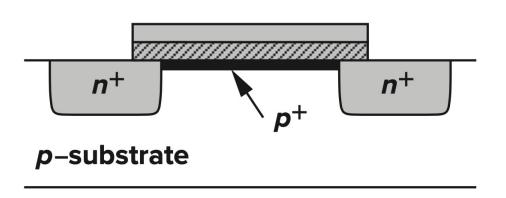
- When interface potential reaches sufficiently positive value, electrons flow from the source to the interface and eventually to the drain.
- This creates a channel of charge carriers (inversion layer) beneath the gate oxide.
- The value of V_G at which the inversion layer occurs is the **threshold voltage** (V_{TH}) .

$$V_{TH} = \Phi_{MS} + 2\Phi_F + \frac{Q_{dep}}{C_{ox}}$$

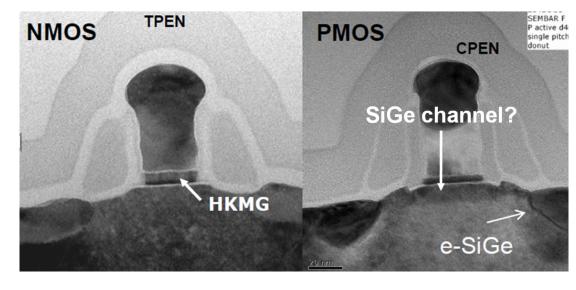
$$\Phi_F = (kT/q) \ln(N_{sub}/n_i)$$
 $Q_{dep} = \sqrt{4q\epsilon_{si}|\Phi_F|N_{sub}}$

Where

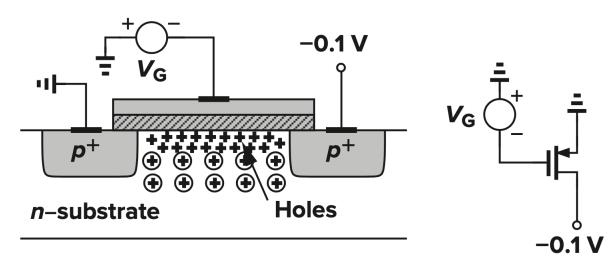
- Φ_{MS} is the difference between the work functions of the polysilicon gate and the silicon substrate.
- k is Boltzmann's constant, q is the electron charge $(kT/q \sim 25 mV)$ at room temp).
- N_{sub} is the doping density of the substrate.
- n_i is the density of electrons in undoped silicon.
- Q_{dep} is the charge in the depletion region.
- C_{ox} is the gate oxide capacitance per unit area.
- ε_{si} is the dielectric constant of silicon.



IBM 32nm CMOS

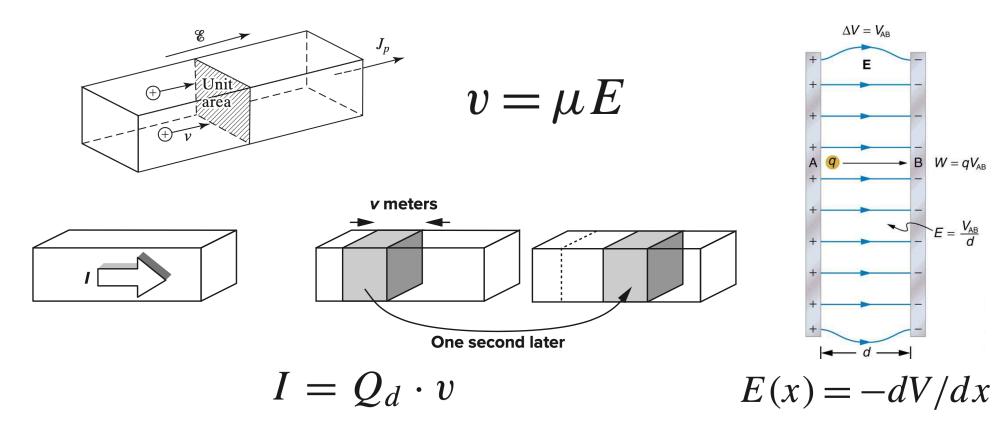


- In practice, threshold voltage is adjusted by implanting dopants into the channel area during device fabrication.
- For NMOS, adding a thin sheet of p^+ increases the gate voltage necessary to deplete the region.

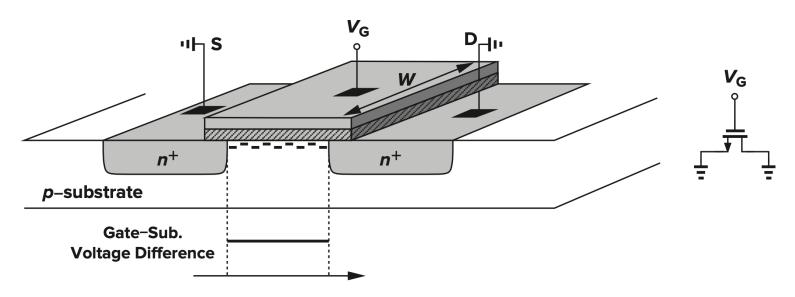


- Turn-on phenomena in PMOS is similar to that of NMOS but with all polarities reversed.
- If the gate-source voltage becomes sufficiently *negative*, an inversion layer consisting of holes is formed at the oxide-silicon interface, providing a conduction path between source and drain.
- PMOS threshold voltage is negative.

Derivation of I/V Characteristics (Basic Eqs.)



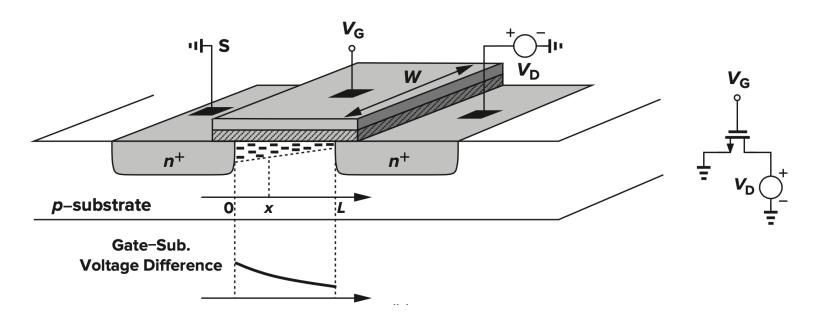
- Where:
 - Q_d is the mobile charge density along the direction of current I.
 - v is the charge velocity & μ is the carrier mobility.



- Onset of inversion occurs at $V_{GS} = V_{TH}$.
- Inversion charge density produced by gate oxide capacitance is proportional to $V_{GS} V_{TH}$ since for $V_{GS} \ge V_{TH}$, charge placed on the gate must be mirrored by charge in the channel, yielding a uniform channel charge density:

$$Q_d = WC_{ox}(V_{GS} - V_{TH})$$

• Where WC_{ox} is the total capacitance per unit length.



- Channel potential varies from zero at the source to V_D at the drain.
- Local voltage difference between the gate and the channel varies from V_G to V_G V_D.
- Charge density now varies with respect to x :

$$Q_d(x) = WC_{ox}[V_{GS} - V(x) - V_{TH}]$$

where V(x) is the channel potential at x.

• Since

$$\begin{cases} I = Q_d \cdot v \\ v = \mu E \end{cases}$$

$$E(x) = -\frac{dV}{dx}$$

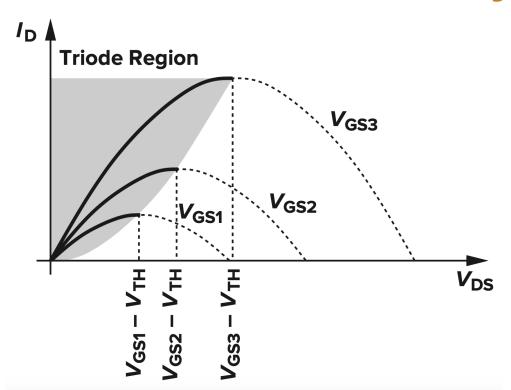
$$Q_d(x) = WC_{ox}[V_{GS} - V(x) - V_{TH}]$$

$$I_D = WC_{ox}[V_{GS} - V(x) - V_{TH}]\mu_n\left(\frac{dV(x)}{x}\right)$$

$$\int_{x=0}^{L} I_D dx = \int_{V=0}^{V_{DS}} WC_{ox}\mu_n[V_{GS} - V(x) - V_{TH}]dV$$

A negative sign is added because the charge carriers are negative for NMOS.

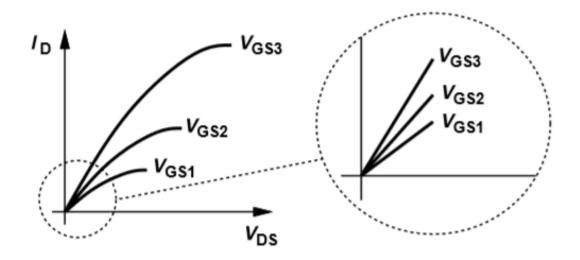
$$I_{D} = \mu_{n}C_{ox}\frac{W}{L}[(V_{GS} - V_{TH}) \cdot V_{DS} - \frac{1}{2}V_{DS}^{2}]$$



$$I_D = WC_{ox}[V_{GS} - V(x) - V_{TH}]\mu_n\left(\frac{dV(x)}{x}\right)$$

$$I_{D,max} = \frac{1}{2}\mu_nC_{ox}\left(\frac{W}{L}\right)(V_{GS} - V_{TH})^2$$

- V_{GS}-V_{TH} is known as the "overdrive voltage." (typically denoted by V_{OD})
- W/L is known as the "aspect ratio."
- If V_{DS} ≤ V_{GS}-V_{TH}, we say the device is operating in the "triode region" (or "linear region")



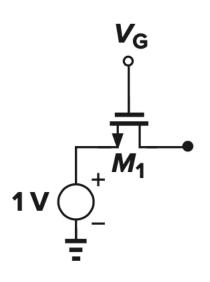
• If
$$V_{DS}$$
 << $2(V_{GS}-V_{TH})$, then $I_D pprox \mu_n C_{ox} rac{W}{L} (V_{GS}-V_{TH}) V_{DS}$

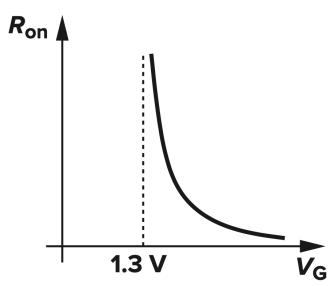
• In this case, the drain current is a linear function of V_{DS} so the path from source to drain can be represented by a linear resistor:

$$R_{on} = \frac{1}{\mu_n C_{ox} \frac{W}{L} (V_{GS} - V_{TH})}$$



- If $V_{DS} \ll 2(V_{GS} V_{TH})$, the device is operating in "deep triode region."
- In this region, a MOSFET can operate as a resistor whose value is controlled by the overdrive voltage.
- Unlike bipolar transistors, a MOS device may be on even if it carries no current.





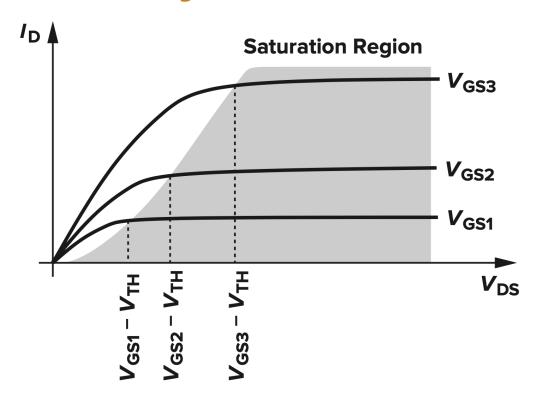
• For example, given the topology on the left and that

$$\mu_n C_{ox} = 50 \,\mu\text{A/V}^2$$

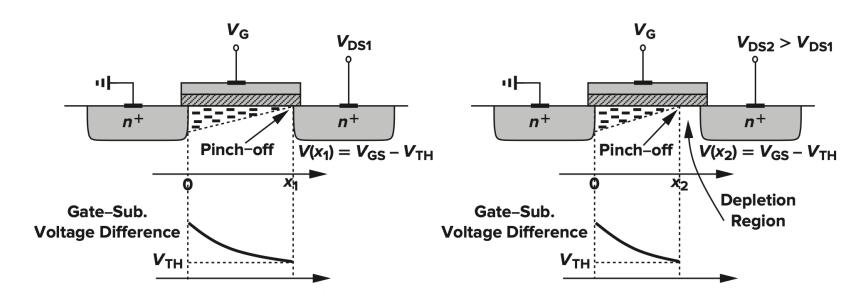
$$W/L = 10$$

$$V_{TH} = 0.3 \text{ V}$$

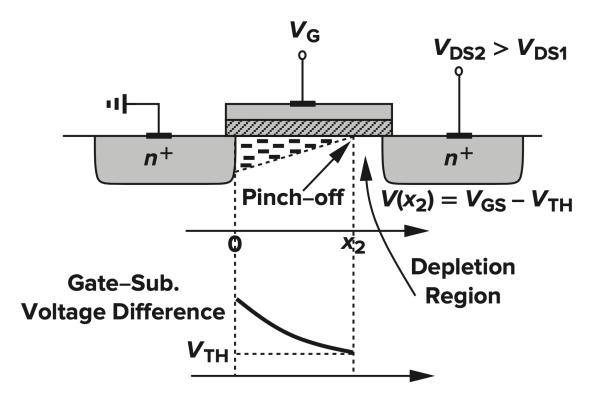
$$R_{on} = \frac{1}{50 \,\mu\text{A/V}^2 \times 10(V_G - 1 \text{ V} - 0.3 \text{ V})}.$$



- In reality, if $V_{DS} > V_{GS} V_{TH}$, I_D becomes relatively constant and we say that the device operates in "saturation region."
- $V_{D.sat} = V_{GS} V_{TH}$ denotes the minimum V_{DS} necessary for operation in saturation.



- If V_{DS} is slightly larger than $V_{GS}-V_{TH}$, the inversion layer stops at $x \le L$, and the channel becomes "pinched off."
- As V_{DS} increases, the point at which Q_D equals zero gradually moves towards the source.
- At some point along the channel, the local potential difference between the gate and the oxide-silicon interface is not sufficient to support an inversion layer.



- Electron velocity ($v = I/Q_d$) rises tremendously as they approach the pinch-off point (where $Q_d \to 0$) and shoot through the depletion region near the drain junction and arrive at the drain terminal.
- Similar to the flow of water in a river reaching a waterfall!

$$V_{GS} = \sqrt{\frac{2I_D}{\mu_n C_{ox} \frac{W}{L'}}} + V_{TH}$$

Since the integral becomes

$$\int_{x=0}^{x=x_2=L'} I_D dx = \int_{V=0}^{V=V_{GS}-V_{TH}} W C_{ox} \mu_n [V_{GS} - V(x) - V_{TH}] dV$$

$$I_D = \frac{1}{2} \mu_n C_{ox} \left(\frac{W}{L'}\right) (V_{GS} - V_{TH})^2$$

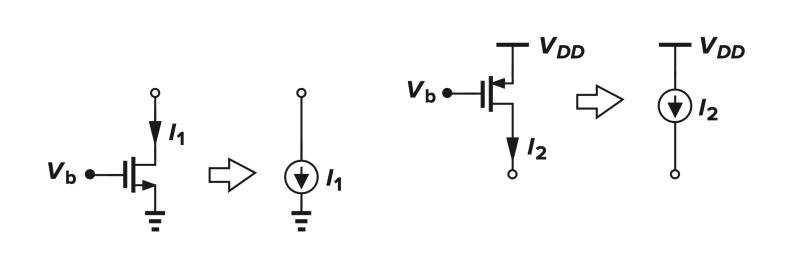
- I_D is relatively independent of V_{DS} if L' remains close to L.
- The device exhibits a "square-law" behavior.

For PMOS devices, the equations become

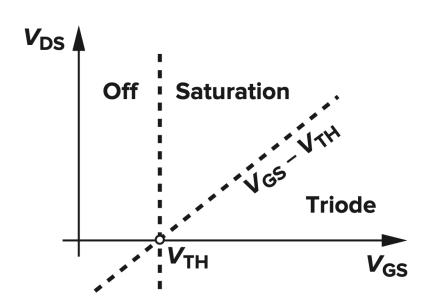
$$I_{D} = -\mu_{p} C_{ox} \frac{W}{L} \left[(V_{GS} - V_{TH}) V_{DS} - \frac{1}{2} V_{DS}^{2} \right]$$

$$I_{D} = -\frac{1}{2} \mu_{p} C_{ox} \frac{W}{L'} (V_{GS} - V_{TH})^{2}$$

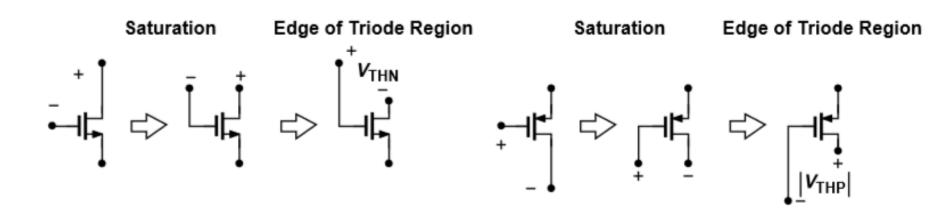
- The negative sign shows up due to the assumption that drain current flows from drain to source, whereas holes in a PMOS flow in the reverse direction.
- V_{GS} , V_{DS} , V_{TH} , and V_{GS} – V_{TH} are negative for a PMOS transistor that is turned on.
- Since the mobility of holes is about ½ the mobility of electrons, PMOS devices suffer from lower "current drive" capability.



- A saturated MOSFET can be used as a current source connected between the drain and the source.
- NMOS current sources inject current into ground while PMOS current sources draws current from V_{DD}.

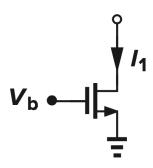


- $V_{DS} = V_{GS} V_{TH} = V_{D,sat}$ is the line between saturation and triode region.
- For a given V_{DS} , the device eventually leaves saturation as V_{GS} increases.
- The drain is defined as the terminal with a higher (lower) voltage than the source for an NMOS (PMOS).



NMOS Example

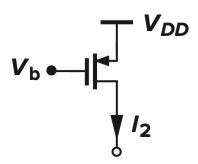
- Calculate I₁ assuming transistor is in the Saturation Region, and ...
 - L = 65nm, W = 1um, $\mu_n C_{ox} = 0.5 \text{mA/V}^2$
 - $V_{th} = 0.6V$, $V_{b} = 1V$



• What are the conditions for the device to operate in saturation?

PMOS Example

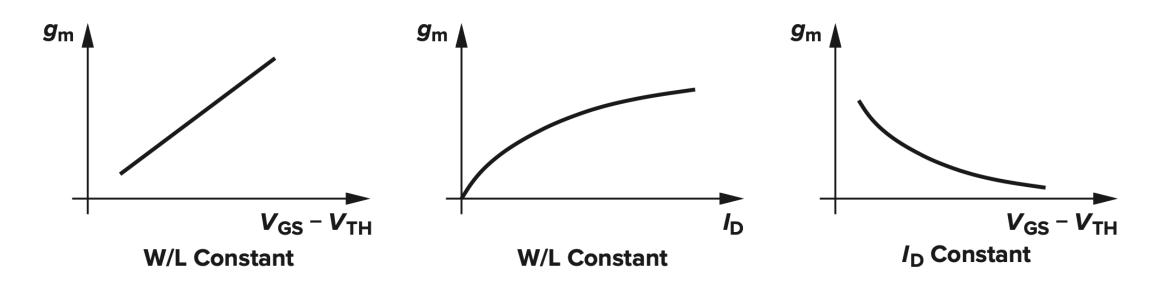
- Calculate I₁ assuming transistor is in the Saturation Region, and ...
 - L = 65nm, W = 1um, $\mu_p C_{ox} = 0.25 \text{mA/V}^2$
 - $V_{th} = -0.6V$, $V_{DD} = 1.2V$, $V_b = 0.2V$



• What are the conditions for the device to operate in saturation?

$$g_{m} = \frac{\partial I_{D}}{\partial V_{GS}} \Big|_{V_{DS} const.} = \mu_{n} C_{ox} \frac{W}{L} (V_{GS} - V_{TH})$$
$$= \sqrt{2\mu_{n} C_{ox} \frac{W}{L} I_{D}} = \frac{2I_{D}}{V_{GS} - V_{TH}}$$

- Transconductance (usually defined in the saturation region) is defined as the change in drain current divided by the change in the gate-source voltage.
- g_m represents the sensitivity of the device since a high value implies a small change in V_{GS} will result in a large change in I_D.
- Transconductance in saturation region is equal to the inverse of R_{on} in the deep triode region.

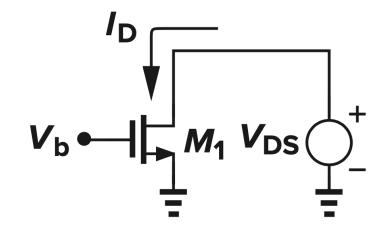


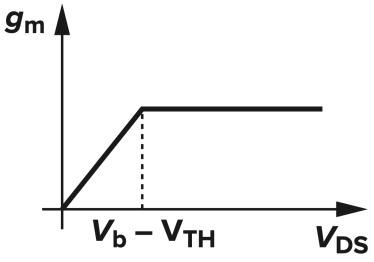
- Each expression for transconductance is useful in studying its behavior.
- Drain current and overdrive voltage are bias values.
- If a small signal is applied to a device with defined bias values, we assume the signal amplitude is small enough that the variation in transconductance is negligible.

- To find the transconductance for the topology on the left with respect to V_{DS},
 - So long as $V_{DS} \ge V_b V_{TH}$, M_1 is in saturation, so I_D is relatively constant, and therefore so is g_m .
 - When M_1 enters triode region ($V_{DS} < V_b V_{TH}$),

$$g_m = \frac{\partial}{\partial V_{GS}} \left\{ \frac{1}{2} \mu_n C_{ox} \frac{W}{L} \left[2(V_{GS} - V_{TH}) V_{DS} - V_{DS}^2 \right] \right\}$$
$$= \mu C_{ox} \frac{W}{L} V_{DS}$$

 We are <u>mostly</u> (in this course) interested in biasing the circuit such that all of MOS devices will be in the saturation regime (why?)





• For PMOS,

$$g_{m} = -\mu_{p} C_{ox} \left(\frac{W}{L}\right) (V_{GS} - V_{TH})$$

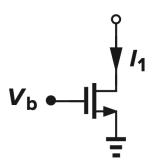
$$= -\frac{2I_{D}}{V_{GS} - V_{TH}}$$

$$= \sqrt{2\mu_{p} C_{ox} \left(\frac{W}{L}\right) I_{D}}$$

• Why the g_m is similar to NMOS (i.e., not negative)?

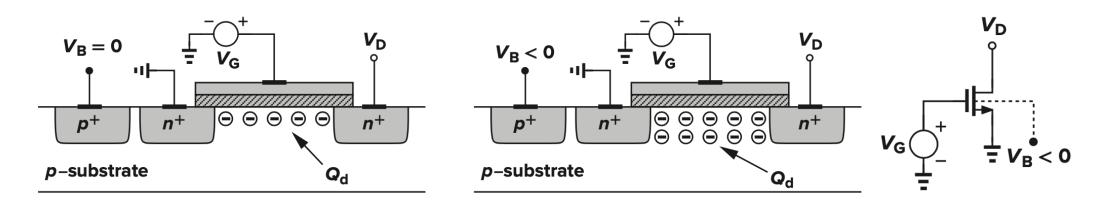
g_m Example

- Calculate g_m assuming transistor is in the Saturation Region, and ...
 - L = 65nm, W = 1um, $\mu_n C_{ox} = 0.5 \text{mA/V}^2$
 - $V_{th} = 0.6V$, $V_b = 1V$



•What should be the unit for g_m?

Second-Order Effects (Body effect)



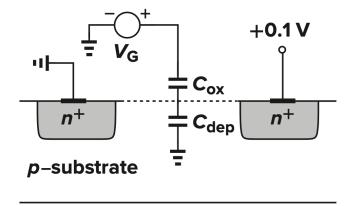
 Originally, with the bulk of an NMOS tied to ground, the threshold voltage was defined as

$$V_{TH} = \Phi_{MS} + 2\Phi_F + \frac{Q_{dep}}{C_{ox}}$$

- Decreasing the bulk voltage (V_B) increases the number of holes attracted to the substrate connection, which leaves a larger negative charge behind and makes the depletion region wider, increasing Q_{dep} and thus increasing V_{TH} .
- This is known as the "body effect" or "back-gate effect." [This turns out to be confusing!!!!]

Second-Order Effects (Body effect)

$$Q_{dep} = \sqrt{4q\epsilon_{si}|\Phi_F|N_{sub}}$$



 With body effect, the expression which characterizes the dependence of threshold voltage on the bulk voltage is

$$V_{TH} = V_{TH0} + \gamma (\sqrt{2\Phi_F + V_{SB}} - \sqrt{|2\Phi_F|})$$

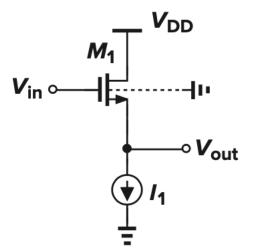
• Where,

$$-V_{TH0} = \Phi_{MS} + 2\Phi_F + \frac{Q_{dep}}{C_{ox}}$$

$$-\gamma = \sqrt{2q\epsilon_{si}N_{sub}}/C_{ox}$$

denotes the body effect coefficient.

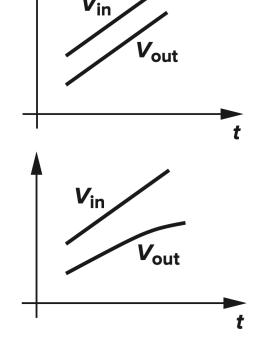
Second-Order Effects (Body effect)



- Body effect manifests itself whenever the source voltage varies with respect to the bulk potential.
- Given the topology on the left and first ignoring body effect, as V_{in} varies, V_{out} follows the input because the drain current remains equal to I_1 , where

$$I_1 = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (V_{in} - V_{out} - V_{TH})^2$$

- With body effect, as $V_{in,out}$ become more positive, V_{SR} increases, which increases V_{TH} and thus V_{in}
 - V_{out} must increase to maintain a constant I_D.



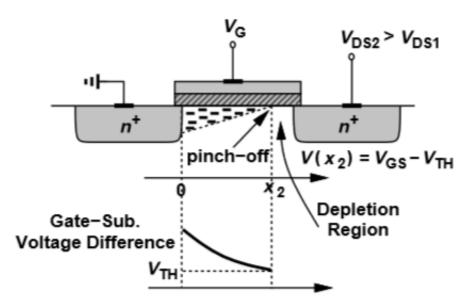
Second-Order Effects (Channel length modulation)

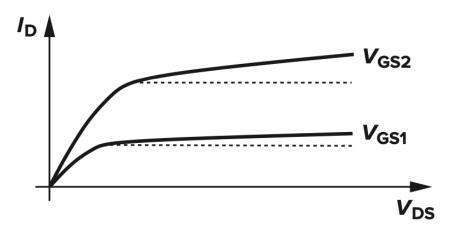
 Originally, when the device was in saturation region, drain current was characterized by

$$I_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L'} (V_{GS} - V_{TH})^2$$

- The actual length of the channel (L' = L Δ L) is a function of V_{DS}, which is an effect called "channel length modulation."
- 1/L' \approx (1 + Δ L/L)/L, and Δ L/L = λ V_{DS}, where λ is the channel-length modulation coefficient. Thus:

$$I_D \approx \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (V_{GS} - V_{TH})^2 (1 + \lambda V_{DS})$$





Second-Order Effects (Channel length modulation)

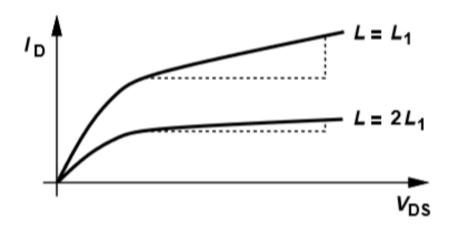
 With the effect of channel length modulation, the expressions derived for transconductance of the device that need modification are

$$g_m = \mu_n C_{ox} \frac{W}{L} (V_{GS} - V_{TH}) (1 + \lambda V_{DS})$$
$$= \sqrt{2\mu_n C_{ox} (W/L) I_D (1 + \lambda V_{DS})}$$

• Notice g_m will be still as shown below, once you consider $(1 + \lambda V_{DS})$ factor in the new I_D :

$$= \sqrt{2\mu_n C_{ox} \frac{W}{L} I_D} = \frac{2I_D}{V_{GS} - V_{TH}}.$$

Second-Order Effects (Channel length modulation)



Knowing that

$$I_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} (V_{GS} - V_{TH})^2 (1 + \lambda V_{DS}) ,$$

$$\lambda \propto 1/L$$

and keeping all other parameters constant, we can see that if the length L is doubled, the slope of I_D vs. V_{DS} is divided by *four*.

• This is due to $\partial I_D/\partial V_{DS} \propto \lambda/L \propto 1/L^2$.